

Form PTO-1449  
(Rev. 8-83)U.S. Department of Commerce  
Patent and Trademark Office

Atty Docket 0756-2222

Serial No. 09/699,466

## INFORMATION DISCLOSURE STATEMENT

Applicants: Shunpei YAMAZAKI et al.

Filing Date: October 31, 2000

Group Art Unit: 2813

## U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date (if appropriate)
AICS	3,389,024	06/18/1968	Schimmer			
AICS	4,472,458	09/18/1984	Sirinyan et al.			
AICS	4,481,121	11/06/1984	Barthel			
AICS	4,735,824	04/05/1988	Yamabe et al.			
AICS	4,911,781	03/27/1990	Fox et al.			
AICS	4,959,700	09/25/1990	Yamazaki			
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AICS	5,089,441	02/18/1992	Moslehi			
AICS	5,354,697	10/11/1994	Oostra et al.			
AICS	5,387,530	02/07/1995	Doyle et al.			
AICS	5,470,763	11/28/1995	Hamada			
AICS	5,508,207	04/16/1996	Horai et al.			
AICS	5,530,266	06/25/1996	Yonehara et al.			
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AKS	5,843,225	12/01/1998	Takayama et al.			
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AICS	02-148687	06/07/1990	JP			Eng Abst	
AICS	05-107561	04/30/1993	JP			Eng Abst	
✓	06-299348	11/12/1993	JP			Eng Abst	
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✓	07-164634	06/23/1995	JP			Eng Abst	
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AICS	Dimitros et al., "Fluorine-Enhanced Oxidation of Polycrystalline Silicon and Application to Thin-Film Transistor Fabrication", pp. 937-937, August 24, 1992, Appl. Phys. Lett. 61 (8)
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AICS	Hayashi et al., "Fabrication of Low-Temperature Bottom-Gate Poly-Si TFTs on Large-Area Substrate by Linear-Beam Excimer Laser Crystallization and Ion Doping Method", pp. 829-832, 1995, IEEE 33.3.1, IEDM 95
AICS	Sakaguchi et al., "Current Progress in Epitaxial Layer Transfer (ELTRAN)", pp. 378-387, March 1997, IEICE Trans. Electron, Vol. E80, No. 3
AICS	Kuper et al., "Effects of Fluorine Implantation on the Kinetics of Dry Oxidation of Silicon", pp. 985-990, August 1, 1986, J. Appl. Phys. 60 (3)
AICS	Wolf et al., "Silicon Processing for the VLSI Era", pp. 198-207, 1965, Lattice Press, Vol. 1, Process Technology

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AICs

Kuo, Y., "Thin Film Transistor Technologies", pp. 116-122 Vol. 94-35

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A. S. H. Umar Saifan

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